



C O F C

PATENT

I hereby certify that on the date specified below, this correspondence is being deposited with the United States Postal Service as first-class mail in an envelope addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

August 31, 2007
Date

ABeggs
Alexandra Beggs

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	: Scott E. Moore	Attorney Docket No.:	500170.05
Patent No.	: US 6,969,297 B2	Serial No.	: 09/782,892
Issue Date	: November 29, 2005	Filed	: February 13, 2001
Title	: APPARATUS AND METHOD FOR CONDITIONING AND MONITORING MEDIA USED FOR CHEMICAL-MECHANICAL PLANARIZATION		

REQUEST FOR CERTIFICATE OF CORRECTION

Certificate

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SEP 06 2007
of Correction

Sir:

A Certificate of Correction under 35 U.S.C. § 254 is respectfully requested for the above-identified patent in order to correct Patent and Trademark Office errors made during the printing of the patent or in the original application. The changes in the patent needed to correct the errors are as follows:

<u>Column, Line</u>	<u>Reads</u>	<u>Should Read</u>
Column 3, Line 5	"Alternatively, (for example,"	--Alternatively (for example,--
Column 3, Line 29	"signal received form"	--signal received from--
Column 5, Line 27	"material removed form"	--material removed from--
Column 6, Line 46	"the two surface."	--the two surfaces.--
Column 6, Lines 47-50	"The relative velocity between the two surfaces can	--The relative velocity between the two surfaces can in turn be a

SEP 6 2007

	in turn be a function of the rotational and/or translational speed of the polishing pad 127, the position of the conditioning body 150 relative to the polishing pad 127.”	function of the rotational and/or translational speed of the polishing pad 127, the rotational and/or translational speed of the conditioning body 150, and the position of the conditioning body 150 relative to the polishing pad 127.”
Column 7, Line 35	“force sensor 180 can be”	--force sensor 180, can be--
Column 8, Line 8	“then toward”	--than toward--
Column 24, Lines 33-40	“a conditioning body adjacent to the planarizing medium, at least one of the conditioning body and the planarizing medium being movable relative to the other of the conditioning body and the planarizing medium for conditioning the planarizing surface, the conditioning body and the planarizing medium generating a force in the planarizing medium moves relative to the other of the conditioning body and the planarizing medium;”	--a conditioning body adjacent to the planarizing medium, at least one of the conditioning body and the planarizing medium being movable relative to the other of the conditioning body and the planarizing medium for conditioning the planarizing surface, the conditioning body and the planarizing medium generating a force in the planarizing surface plane when the one of the conditioning body and the planarizing medium moves relative to the other of the conditioning body and the planarizing medium;”
Column 24, Line 52	“detect the force; the sensor”	--detect the force, the sensor--
Column 27, Line 57	“the sensor is positioned”	--the sensor positioned--

The above errors for which correction is requested under 35 U.S.C. § 254 were made in the printing of the patent or in the original application. The errors are considered

SEP 6 2007

sufficiently important to justify the processing of a Certificate of Correction under 35 U.S.C. § 254. A Form PTO-1050, in duplicate, is enclosed herewith.

The Commissioner is hereby authorized to charge payment of any fees associated with this communication to Deposit Account No. 50-1266. A duplicate copy of this sheet is enclosed.

Favorable consideration of this Request is respectfully requested.

Respectfully submitted,

Date:

Aug. 29, 2007

By:

Edward W. Bulchis

Edward W. Bulchis, Reg. No. 26,847

Customer No. 27,076

Dorsey & Whitney LLP

1420 Fifth Avenue, Suite 3400

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Attorney for Applicant(s)

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Enclosures:

Postcard

Form PTO-1050 (+ copy)

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SEP 6 2007

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CERTIFICATE OF CORRECTION**

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DATED : November 29, 2005
INVENTOR(S) : Scott E. Moore

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MAILING ADDRESS OF SENDER:

DORSEY & WHITNEY LLP
1420 Fifth Avenue, Suite 3400
Seattle, Washington 98101

Patent No. US 6,969,297 B2

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FORM PTO-1050 (REV. 3-82)

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